LISTING OF THE CLAIMS

This listing of claims will replace all prior versions, and listings, of claims in the application:

Claims 1-10 (Canceled)

Claim 11 (Currently Amended)

A substrate treating apparatus for performing a predetermined treatment of substrates ~~as immersed in a treating liquid stored in a treating tank~~, comprising:

a treating tank for immersing the substrates in a treating liquid stored therein;

a holding arm for holding the substrates in vertical posture, said holding arm being movable to a treating position in said treating tank for immersing the substrates in the treating liquid;

a storage device which stores ~~means for storing~~ a relationship between use history and treating rate of the treating liquid and an up-to-date use history of the treating liquid;

a calculating device which derives ~~means for deriving~~ a current treating rate from said relationship between use history and treating rate of the treating liquid and said up-to-date use history of the treating liquid; and

a computing device which determines ~~means for determining~~ a corrected treating time by extending a predetermined treating time according to said current treating rate;

wherein said substrates are treated for said corrected treating time.

Claim 12 (Currently Amended)

A apparatus as defined in claim 11, wherein said calculating device ~~means~~ is arranged to take into account at least one of a treated number of substrates, a treating rate, a treating time, a substrate type, a rate of over-treatment, a substrate coverage of film and an initial treating rate.

Claim 13 (Currently Amended)

A apparatus as defined in claim 11, wherein said calculating <u>device</u> ~~means~~ is arranged to take into account at least one of a treated number of substrates, a treating time and a substrate coverage of film.

Claim 14 (Currently Amended)

A apparatus as defined in claim 11, wherein said calculating <u>device</u> ~~means~~ is arranged to derive said corrected treating time from;

$$A1 = Ti \bullet (Ri/Rm)$$

where Ti is an etching time specified in a recipe with reference to a fresh portion of said treating liquid, Ri is an etching rate of the fresh portion, and Rm is the current etching rate.

Claim 15 (Currently Amended)

A apparatus as defined in claim 12, wherein said calculating <u>device</u> ~~means~~ is arranged to derive said corrected treating time from;

$$A1 = Ti \bullet (Ri/Rm)$$

where Ti is an etching time specified in a recipe with reference to a fresh portion of said treating liquid, Ri is an etching rate of the fresh portion, and Rm is the current etching rate.

Claim 16 (Currently Amended)

A apparatus as defined in claim 13, wherein said calculating <u>device</u> ~~means~~ is arranged to derive said corrected treating time from;

$$A1 = Ti \bullet (Ri/Rm)$$

where Ti is an etching time specified in a recipe with reference to a fresh portion of said treating liquid, Ri is an etching rate of the fresh portion, and Rm is the current etching rate.

Claim 17 (Original)

A apparatus as defined in claim 11, wherein said treating liquid includes phosphoric acid.

Claim 18 (Original)

      A apparatus as defined in claim 12, wherein said treating liquid includes phosphoric acid.

Claim 19 (Original)

      A apparatus as defined in claim 14, wherein said treating liquid includes phosphoric acid.

Claim 20 (Original)

      A apparatus as defined in claim 11, wherein said treating liquid includes hydrofluoric acid.